

In re: *Kong et al.*
Appl. Serial No. 09/715,576
Filed: November 17, 2000
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Amendments to the Claims:

This listing of Claims will replace all prior versions, and listings, of claims in the application:

Claims 1-21 (canceled)

Claim 22 (previously presented): A chemical vapor deposition system according to Claim 49 wherein said reaction vessel is made of quartz.

Claim 23 (canceled)

Claim 24 (previously presented): A chemical vapor deposition system according to Claim 49 wherein said source of electromagnetic radiation comprises an induction coil surrounding said reaction vessel.

Claims 25-48 (canceled)

Claim 49 (previously presented): A chemical vapor deposition system consisting essentially of:

a reaction vessel formed of a material substantially transparent to electromagnetic radiation;

a gas supply system in fluid communication with said reaction vessel;

a source of electromagnetic radiation external to said reaction vessel; and

a susceptor within said reaction vessel, said susceptor formed of a material that is thermally responsive to electromagnetic radiation, wherein said susceptor is defined by a plurality of straight sidewall sections, each section having a planar surface, with said